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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of : **MAIL STOP: AMENDMENT**
Norio KIMURA et al. : **Confirmation No. 9675**
Serial No. 10/784,945 : Docket No. 2004_0201
Filed February 25, 2004 : Group Art Unit 3723
POLISHING APPARATUS AND METHOD : Examiner E.P. MORGAN

AMENDMENT AND RESPONSE TO RESTRICTION REQUIREMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

THE COMMISSIONER IS AUTHORIZED
TO CHARGE ANY DEFICIENCY IN THE
FEES FOR THIS PAPER TO DEPOSIT
ACCOUNT NO. 23-0975

Sir:

This is in response to the Restriction Requirement of September 8, 2004.

Applicants, by their undersigned representative, hereby elect the invention of Group I which is drawn to a method of surface and outer peripheral polishing by claims 1-5, 17 and 20.

Also, claims 21 and 22 have been added.

Having made the required election, a full examination on the merits of the elected invention is hereby requested.